

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

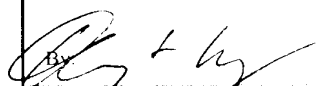
Inventor(s) : Valerie S. SMIRNOV et al.
International Appln. No. : PCT RU01 00261
International Filing Date : July 2, 2001
U.S. Appln. No. : 10 069,656
Filing Date : February 25, 2002
For : DEVICE FOR FORMING NANOSTRUCTURES
ON THE SURFACE OF A SEMICONDUCTOR
WAFER BY MEANS OF ION BEAMS

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SIR:

Transmitted herewith is a Power of Attorney by Assignee of Entire Interest for filing
in: the above-identified application.

Respectfully submitted,

Dated:

June 19, 2002

By: 

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